

SURFACE DISTORTION COMPENSATED PHOTOLITHOGRAPHY

ABSTRACT

A distortion compensation system for use in an imaging device such as a photolithography system is described. The system projects a plurality of image portions onto a plurality of portions of a subject. The system includes a plurality of light-distance modulators corresponding to the plurality of image portions and a mechanical manipulator for individually manipulating each of the light-distance modulators. In this way, any distortion in the subject is compensated by the individual manipulation of the light-distance modulators.